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Toyohashi University of Technology, JAPAN

IEEE MEMS 2023 Announcement

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Núria Barniol, *Universidad Autonoma Barcelona, SPAIN*
Franz Lärmer, *Bosch, GmbH, GERMANY*

Awards Ceremony and Closing Remarks

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533-h	A DUAL-BAND TERAHERTZ FOCAL PLANE ARRAY FOR MATERIAL COMPOSITION IDENTIFICATION BY SPECTRAL IMAGING 1054 Jia Xu, Jiahao Miao and Yi Liu, and Xiaomei Yu <i>Peking University, CHINA</i>
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